

Cornell Laboratory for Accelerator-based Sciences and Education (CLASSE)

Update of Vertical Electro-Polishing Studies at Cornell with KEK and Marui Galvanizing Co. Ltd

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Introduction

Cornell, KEK, and Marui Galvanizing Co. Ltd have started Vertical Electro-Polishing (VEP) R&D collaboration in 2014 to



Images of VEP cathode

Cornell cathode



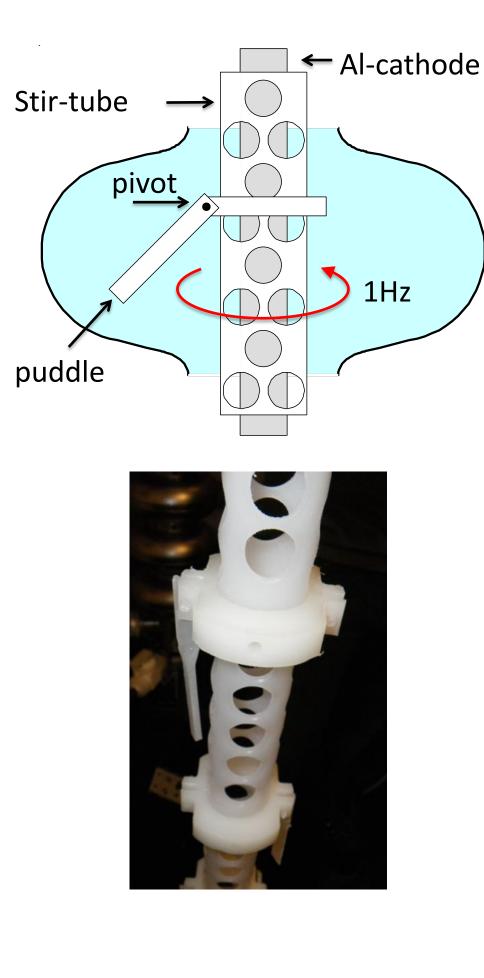
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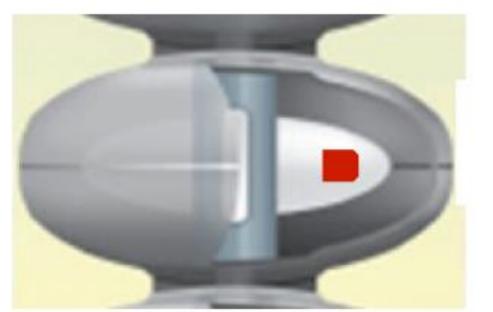
improve the removal uniformity. MGI and KEK have developed their original VEP cathode named i-cathode Ninja[®], which has four retractable wing-shape parts per cell. One single cell cavity, NR1-2, has been processed with VEP using the i-cathode Ninja at Cornell. Cornell also performed the vertical test on that cavity. We present the details of the process and RF test results at Cornell.

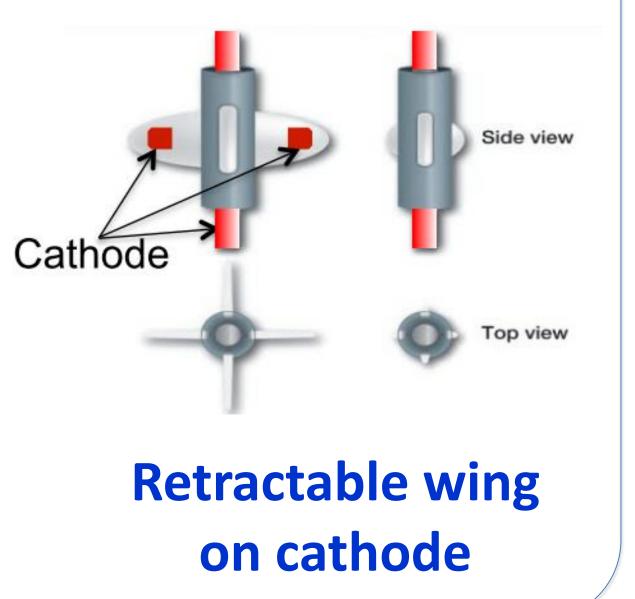
Installation of "Ninja"-cathode into Cornell VEP system

- Two type of Ninja-cathodes and top/bottom EP sleeves were provided from Marui.
- Upgraded the acid tubing to make acid circulation during VEP.
- EP control system, acid tank, circulation pump, water cooling, I-V source, were used without any changes.









VEP parameters and results at Cornell

VT results at 2K

KFK-Marui

1.00E+11 –

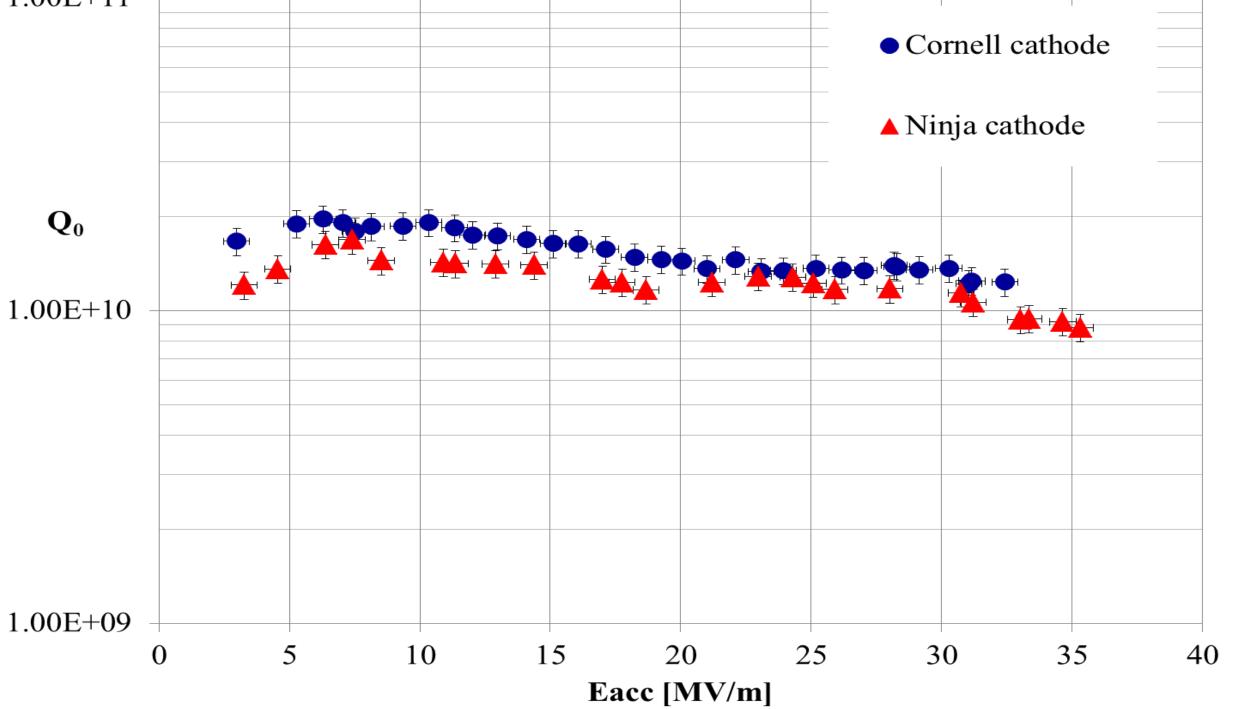
Parameter comparison		Cornell	KEK-IVIALUI	
			Ninja type-1	Ninja type-2
Electrolyte composition		9:1 (H ₂ SO ₄ : HF in weight)		
Voltage		14Volts	14Volts	14Volts
Current ave. (single cell EP)		~17Amps.	~22Amps.	~29Amps.
Temp. (cavity outside)		17~18degC	20~25degC	20~25degC
Acid circulation		None	~5L/min.	~5L/min.
Agitation speed		0~1Hz	0.8Hz	0.8Hz
Puddle type /cell		1 Teflon puddle	4 Teflon wing w/ Al	4 Teflon wing
Teflon cathode bag		Yes	None	Yes
Removal* (preliminary)	target		20um	
	Top half	24um	36um	29um
	Bottom half	14um	20um	18um

- Target removal was calculated from the current integration during the process.
- Measurements on top/bottom half cell was done by ultra-sound thickness gauge after the process.

Process notes for VT

3. VT post Ninja VEP

Step	Surface preparations
1. VT post Cornell VEP	Bulk VEP (120μm)+ degas + light VEP (20μm)+ 120C*48hrs baking
2. Reset surface	Tumbling (40μm) + BCP(60μm) + degas (800C*2hrs)



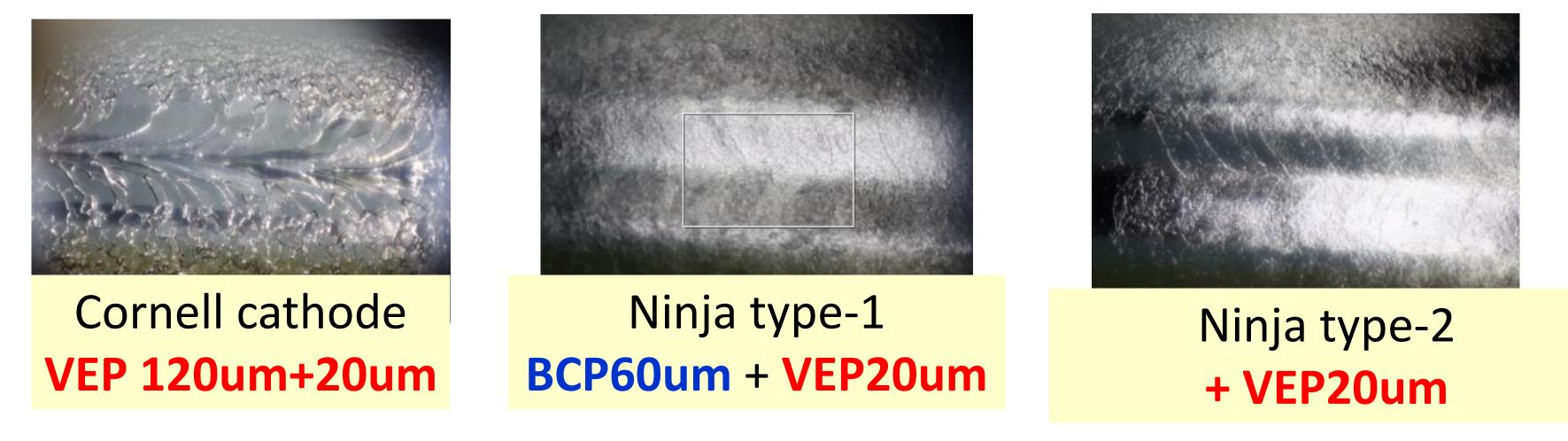
Both tests were limited by quench, field emission free.

Summary

- The integration of the Ninja cathode into the Cornell VEP system and VEP process had been done successfully at Cornell.
- This is the first trial to use Ninja cathode at Cornell. The parameters were set based on Marui's experiments, but not optimized for Cornell's system yet.

+ VEP (20µm) w/ Ninja cathode type-1 + VEP (20µm) w/ Ninja cathode type-2 + 120C*48hrs baking.

Optical inspection images of equator weld seam on RF surface



- Similar defects or features were seen on both surfaces after Cornell and Ninja VEP by optical inspection.
- RF test on single cell processed with Ninja cathodes was performed. The result was good and comparable to Cornell VEP.
- The development of a 9-cell scale Ninja cathode and a parametric study of removal uniformity for 9-cell is in progress at Marui and KEK. The 9-cell process with Ninja cathode at Cornell is planned for the future.
- Work is supported by JFY2015 US/Japan Program for **Cooperation in High Energy Physics.**



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